



MODEL 1070

NanoClean

Cleans specimens and holders immediately before insertion into an electron microscope; removes existing carbonaceous debris from the specimen and prevents contamination during imaging and analysis.

Model 1070 NanoClean Specifications

Plasma system

High frequency (13.56 MHz) power amplifier inductively coupled to a quartz and stainless steel plasma chamber

Ion energies less than 12 eV as a function of the downstream plasma

Automatic matching network

Compatible with TEM specimen holders for transmission electron microscopes manufactured by:

- FEI Company/Philips Electron Optics
- Hitachi High Technologies America Inc.
- JEOL Ltd.
- Carl Zeiss Microscopy

Vacuum system

Oil-free turbomolecular drag pump and a multistage diaphragm pump

Vacuum load lock

Ultimate vacuum of 1×10^{-6} mbar

Chamber

Accepts two specimen holder ports

Chamber lid provides access for bulk objects up to 3.5 in (8.9 cm) diam

Viewport for chamber observation

Gas

Three gas inputs

Nominal 10 psi (200 kPa) delivery pressure

Flow rate is controlled by the embedded module

Model 1070 NanoClean Specifications

User interface	Programming through a touch screen embedded module Dedicated recipes for electron microscopy specimen and grid processing Ability to customize parameters Process timer for automatic termination
Dimensions	27 in (69 cm) width x 22 in (56 cm) height x 23 in (59 cm) depth
Weight	160 lb (73 kg)
Power requirements	100/120/220/240 V AC, single phase, 660 W
Warranty	One years

